

## ABSTRACT OF THE DISCLOSURE

The present invention provides a sputtering target for production of a magnetic recording medium including  
5 at least a nonmagnetic undercoat layer, a magnetic layer, and a protective layer laminated sequentially on a nonmagnetic substrate, the sputtering target being used for film formation of the magnetic layer, the sputtering target comprising a mixture of a metal and an oxide, and  
10 the particle diameter of the oxide in the sputtering target being 10  $\mu\text{m}$  or less. The sputtering target suppresses abnormal discharge occurring during film formation of a granular magnetic layer of the magnetic recording medium, and suppresses occurrence of foreign objects on the  
15 magnetic recording medium.